## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Rodney Smedt et al.

Application No.: 10/714,460

Filed: November 14, 2003

For: MEASUREMENT OF OVERLAY USING DIFFRACTION GRATINGS WHEN OVERLAY EXCEEDS THE GRATING PERIOD



Group Art Unit: Unknown

Examiner: Unknown

INFORMATION DISCLOSURE **STATEMENT** 

> 121 Spear Street, Suite 290 San Francisco, CA 94105 (415) 512-1312

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on January 16, 2004. STALLMAN & POLLOCK LLP

Georgia K Stith

Sir:

Applicant(s) submit(s) herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which they are aware, which they believe(s) may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

- (a) accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).
- (b) \( \sum \) is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.
- (c) as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits, or before a first office action after filing a Request for Continued Examination under §1.114.
- (d) is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is

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known to the undersigned, prior to the mailing date of either a final rejection or a notice of allowance, whichever occurs first, and is accompanied by either the fee (\$180) set forth in 37 CFR § 1.17(p) or a certification as specified in 37 CFR § 1.97(e), as checked below.
(e) is filed after the mailing date of either a final rejection or a notice of allowance, whichever occurred first, and the Issue Fee has not been paid, and is accompanied by the fee (\$130) set forth in 37 CFR § 1.17(i)(1) and a certification as specified in 37 CFR § 1.97(e), as checked below. This document is to be considered as a petition requesting consideration of the information disclosure statement.
<ul> <li>(f)  Each item of information contained in the information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.</li> <li>(g)  No item of information contained in this information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned after making reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this information disclosure statement.</li> </ul>
A copy of the items on PTO-1449 (Modified) is supplied herewith, except as noted below.
Those patent(s) or publication(s) which are marked with an asterisk (*) in the attached form PTO-1449 (Modified) are not supplied because they are (a) either U.S. Patents and this an application filed after June 30, 2003, or (b) were previously cited by or submitted to the Office in a prior application no, filed and relied upon in this application for an earlier filing date under 35 U.S.C. § 120.  A concise explanation of relevance of the items listed on form PTO-1449 (Modified) is:

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<b>(1)</b>	given for each listed item
(m)	given for only non-English language listed item(s) [Required]
(n)	is in the form of an English language copy of a Search Report from a foreign
	patent office, issued in a counterpart application, which refers to the relevant
	portions of the references [copy attached].

The Examiner is reminded that a "concise explanation of the relevance" of the submitted items "may be nothing more than identification of the particular figure or paragraph of the patent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

The Commissioner is hereby authorized to charge our Deposit Account No. 50-1703, under Order No. [Client No. ]TWI-33110, for any fees required in connection with the filing of this Information Disclosure Statement. A duplicate copy of this Notice is enclosed for this purpose. In particular, in the event that an Office Action has crossed in the mail with this Information Disclosure Statement, the Commissioner is authorized to charge the above-named deposit account for any fees required pursuant to CFR §§ 1.17(p) or 1.17(i)(1).

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: January / 2004

Michael A. Stallman (Reg. No. 29,444)

Attorneys for Applicant(s)

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## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)
TWI-33110
Applicant(s)
Rodney Smedt et al.
Filing Date
November 14, 2003

JAN 2 0 2004

Application Number 10/714,460

U.S. PATENT DOCUMENTS

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## FOREIGN PATENT DOCUMENTS

REF AQ	DOCUMENT NUMBER WO 02/25723 A2	DATE 03/28/2002	COUNTRY PCT	CLASS H01L	SUBCLASS	TRANS YES	LATION NO
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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AR  H-T. Huang et al., "Scatterometry-Based Overlay Metrology," Metrology, Inspection, and Process Control for Microlithography XVII, Proceedings of SPIE, Vol. 5038 (2003), pp. 126-137.  P. Heimann, "The Color-Box alignment vernier: a sensitive lithographic alignment vernier read at low magnification,"  Optical Engineering, Vol. 29, No. 7, July 1990, pp. 828-836.  K.M. Monahan, "Handbook of Critical Dimension Metrology and Process Control," Critical Reviews of Optical Science and Technology, SPIE, Vol. CR52, proceedings of a conference held 28, 20 Sentence 1002.			, and, entire ruges, Etc.)
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Examiner	T
	Date Considered
Examiner: Initial if citation considered, whether or not citation is in c not in conformance and not considered. Include copy of this form wit	onformance with MPEP Section 609; Draw line through citation if hext communication to applicant.